

**Notice of References Cited**

Application/Control No.

09/595,778

Applicant(s)/Patent Under

Reexamination

GRIMBERGEN ET AL.

Examiner

Allan Olsen

Art Unit

1792

Page 1 of 1

**U.S. PATENT DOCUMENTS**

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
U	Barna et al., In Situ Metrology, pages 35-44 of Chapter 22 of Handbook of Silicon Semiconductor Metrology, Edited by Alain Diebold, 2001(Marcel Dekker Inc)
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

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